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\mathcal{W}	-	\dashv	S. Callard, et al., "New method for in situ control of Bragg reflector fabrication," Applied Physics Letters, American Institute of Physics, New York, US, vol. 65, pp. 17, April 22, 1996, pp. 22, 23, 23, 23, 23, 24, 24, 25, 26, 27, 28, 28, 28, 28, 28, 28, 28, 28, 28, 28														
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